

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In the PATENT APPLICATION Of:

Group Art Unit: 1756
Examiner: To Be Assigned

#5

Applicants : Minoru WATANABE)
Serial No. : 10/025,783)
Filed : December 26, 2001)
For : METHOD AND APPARATUS FOR)
FORMING RESIST PATTERN)
Attorney Ref. : MAE 223 C1)

INFORMATION
DISCLOSURE
STATEMENT

May 22, 2002

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TC 1700

Commissioner of Patents
Washington, D.C. 20231

Sir:

This is an information disclosure statement submitted in compliance with the timing requirements of 37 C.F.R. §1.97(b)(3), i.e., prior to a First Office Action on the Merits.

Attached are copies of one U.S. patent document, and two Japanese patent publications, the relevance of which may be gleaned from the English-language translations. The publications are listed on the attached Form PTO-1449.

Since this Information Disclosure Statement is being filed before the First Office Action, no certification or fee is required, and the requirements of 37 C.F.R. §§1.97 and 1.98 are deemed to be fully met as to all documents submitted. Consideration of the submitted documents is respectfully requested.

Respectfully submitted,

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